: Y - 89-218627

- VACUUM PROCESSOR CAPABLE OF PLURAL PROCESSING
- 🐃 (2000510) HITACHI LTD
- DV XZUNO, JINICHI
- TV 89.08.31 J01218627, JP 01-218627
- 95 58.02.29 88UP-044396, 63-44396
- 17 39.11.28 SECT. C, SECTION NO. 659; VOL. 13, NO. 532, PG. 137.
- 10 Boid-008/02
- 5. 13.1 (INORGANIC CHEMISTRY--Processing Operations); 42.2 (ELECTRONICS--Solid State Components)
- ** PRPOSE: To aim at a plurality of efficient evacuating processes in the same vacuum container, by subjecting an article to be evacuated to different processes by being moved in the same vacuum container and preventing evacuating spaces from being contaminated by one another with the use of separating plates between the evacuating spaces in combination with movable shielding plates.

OCNSTITUTION: There are provided an article 1 to be evacuated, a holder 2 thereof, a cover 3 for enclosing the region of the article other than the holder attached surface and a plurality of evacuating spaces A-D between the cover and the wall of a vacuum container 6. The article 1 is moved continuously through a plurality of the evacuating spaces by the the rotation of the holder 2 and the cover 3. Also provided are a pair of separating which 7 and 8 oppositely positioned with a small space between each evacuating space and near the opening of the cover 3 movable chielding plate 10 which is moved in such position as to avoid interference with the separating plates upon movement of the applicate to the adjoining space and, after its movement, in such position as to shielded the separating plates alternately. As a result, a plurality of efficient evacuating processes can be effected in the same vacuum container.

SS 2 /C? USER: FILE JAPIO

250G1

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88 2 /C7 HEER: FILE WPAT

FROGS

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COVERS 1963 THRU WEEKLY UPDATE 9309/UP, 9309/UPEQ, 9251/UPA, 9224/UPB; WPI 9304/UPEQ.

DS 1 /07 HRER: DE2454544/PN

9800: Jun 1 **Peto (1)** .

88 2 709 UPEP: IT FU

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#N: - 75-G0129W/23 (G0129W)

- Coating application system under vacuum - has item mountings Serming working chamber sealed from main one

-- 978 P42

-> -> (POLV) BALZERS VAKUUM GMBH; (BALZ) BALZERS PATENT AG

-- (=) ***

-N - NE7400848-A 75.05.26 (7523) DE2454544-A 75.07.31 (7532)

FR2252419-A 75.07.25 (7537)

(19/3915117-A 75.10.28 (7545)

09-573985-A 76.03.31 (7619)

PRIAGAT90-A 77.03.09 (7710)

DR2454544-B 78.07.13 (7829) Ni-145224-B 80.10.15 (8045)

- 72.11.22 73CH-016602

7 - 3050-013/00 B44D-003/22 C23C-013/08

- (NL7400848)

The mechanism has a number of working stations, partly acting as sludges through which the items are received and discharged, and partly as processing stations for the items under vacuum, also a retary transporter for the items working in a main chamber which and be placed under vacuum. At one or more working stations the mountings for the items form a frame-type wall of a working chamber which can be sealed off from the main one. The chamber has a valve plate, permanently providing a vacuum-tight seal from The upper and lower edges of the wall can have the main one. scaling surfaces pressed against mating surfaces on the ValVe plate and the stationary part of the processing chamber. mountings for the items can slide axially in relation to the transporter.

118/719,730,733

88 2 /07 USER: STOP Y

FROGE

(CENTRAL TIME) TERMINAL SESSION FINISHED 04/23/93 8:05 A.M. ELAPSED TIME ON WPAT: 0.02 HRS. ELAPSED TIME THIS TERMINAL SESSION: 0.05 HOURS. DABIT SEARCH SESSION COMPLETED. THANKS FOR USING ORBIT!

TYMNET: call cleared by request